Agent's Docket No: ONX-113/DIV

In the United States Patent and Trademark Office

Application No TRADE 10/747,875

Filed: December 29, 2003

Title: PWM-Based Measurement Interface for a Micro-Machined Electrostatic Actuator

Applicant: David Horsley et al.

Examiner: Not Yet Assigned Express Mail Label Number: <u>ED 047416615 US</u>

Art Unit 2853

Mailed: <u>July 9, 2004</u>

Fremont, CA

Information Disclosure Statement

Commissioner of Patents and Trademarks Washington, District of Columbia 20231

Dear Sir or Madam:

Attached is a completed Form PTO-1449 and copies of the pertinent parts of the references cited thereon. It is requested that the document(s) on the enclosed form be made of record.

Part I (Authority)

This statement is filed pursuant to:

(X) 37 C.F.R. § 1.97(b).

This information disclosure statement is filed either (1) within three months of the filing date of the national applications; (2) within three months of the date of entry of the national stage as set forth in 37 C.F.R. § 1.491 in an international application; (3) before the mailing date of a first office action on the merits; or (4) before the mailing of a first Office action after the filing of a request for continued examination under §1.114, whichever event occurs last.

Accordingly, this information disclosure statement requires no fee and no certification.

() 37 C.F.R. § 1.97(c).

This information disclosure statement is filed after the period specified in 37 C.F.R. § 1.97(b), but before the mailing date of either (1) a final action under 37 C.F.R. § 1.113 or (2) a notice of allowance under 37 C.F.R. § 1.311.

Accordingly, this information disclosure statement requires either the fee specified in 37 C.F.R. § 1.17(p) for submission of an information disclosure statement under 37 C.F.R. § 1.97(c) (\$180), or a certification according to 37 C.F.R. § 1.97(e).

() 37 C.F.R. § 1.97(d).

This information disclosure statement is filed after the period specified in 37 C.F.R. § 1.97(c). Accordingly, this information disclosure statement requires the petition fee specified in 37 C.F.R. § 1.17(p) to consider an information disclosure statement under 37 C.F.R. § 1.97(d) (\$180) and a certification according to 37 C.F.R. § 1.97(e).

Conditional Petition

It is respectfully requested that this information disclosure statement be considered, good cause being presented in Part III herein (certification). Please treat this paper as the required petition.

If this statement crosses in the mail with an office action, or is otherwise not in the indicated category of 37 C.F.R. § 1.97, it is respectfully requested that this statement be treated in the next appropriate category and made of record.

To the extent required, please treat this paper as a conditional petition for acceptance of the information disclosure statement.

Part II (Payment)

A chec	k is enc	losed as indicated:							
	(X)	No fee is due.							
	()	The fee specified in 37 C.F.R. § 1.17(p) for submission of an information disclosure statement und 37 C.F.R. § 1.97(c) is enclosed (\$180).							
	()	The p etition fee specified in 3 7 C.F.R. § 1.17(p) to consider an information disclosure statement under 37 C.F.R. § 1.97(d) is enclosed (\$180).							
Pursua	nt to 37	Part III (Certification) C.F.R. § 1.97(e), I certify:							
	(X)	No certification is necessary.							
	()	(1) Each item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the statement.							
		() The "communication from a foreign patent office" referred to in the certification is an International Search Report, possibly issued by the U.S. Patent and Trademark Office in its capacity as an International Search Authority or International Preliminary Examining Authority.							
		() The "counterpart foreign application" referred to in the certification corresponds to an ancestor or descendent application of the application for which this information disclosure statement is filed.							
	()	(2) No item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application, or, to my knowledge after making reasonable inquiry, was known to any individual designated in 37 C.F.R. § 1.56(c), more than three months prior to the filing of the statement.							
An add	itional s	Part IV (Additional Statement) tatement regarding these items of information () is, (X) is not, enclosed.							
	Copies	of the cited art references() are enclosed,							
	Copies will be	of the cited art references A through $R(X)$ are of record in parent application Serial No. $\underline{10/012,688}$ and provided if the Examiner deems it convenient.							
		of the cited art references () are not required under 37 CFR 1.98(a)(2)(i) because they are U.S. and/or U.S. Patent Publications and							
	() tl	ne present application was filed after June 30, 2003, or							
		ne present application is an international application that entered the national stage under 35 USC 371 after une 30, 2003.							
Dated:	7/	Respectfully submitted, John D. Janley Joshua D. Isenberg Reg. No. 41,088 204 Castro Lane Fremont, CA 94539 tel: (510) 896-8328 fax: (510) 360-9656							

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